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Attorney Docket: 071469-0308969  
Client Reference: FKL-020

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of: FUKIAGE  
Application No.: 10/812,354

Confirmation Number: 4104  
Group Art Unit: 1762

Filed: March 30, 2004

Examiner:

Title: METHOD OF IMPROVING THE WAFER TO WAFER UNIFORMITY AND  
DEFECTIVITY OF A DEPOSITED DIELECTRIC FILM

PRELIMINARY AMENDMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Before beginning examination, please amend the above-identified application as  
follows:

02/17/2005 SZEWDIE1 00000146 033975 10812354  
01 FC:1202 50.00 DA